

<b>INFORMATION DISCLOSURE CITATION PTO-1449</b>		Customer Number: <b>26615</b>	<b>ATTORNEY'S DKT NO.</b> <b>H1174</b>	<b>APPLICATION NO.</b> <b>Unassigned</b>			
<b>U.S. PATENT DOCUMENTS</b>							
<b>EXAMINER'S INITIALS</b>	<b>PATENT NO.</b>		<b>DATE</b>	<b>NAME</b>	<b>CLASS</b>	<b>SUBCLASS</b>	<b>FILING DATE</b>
<b>FOREIGN PATENT DOCUMENTS</b>							
<b>EXAMINER'S INITIALS</b>	<b>PATENT NO.</b>	<b>DATE</b>	<b>COUNTRY</b>	<b>CLASS</b>	<b>SUBCLASS</b>	<b>Translation</b> <input type="checkbox"/> Yes <input type="checkbox"/> No	
<b>OTHER DOCUMENTS (including Authors, Title, Date, Paragraph, Pages, Etc.)</b>							
<i>FS</i>	Digh Hisamoto et al., "FinFET-A Self-Aligned Double-Gate MOSFET Scalable to 20 nm," IEEE Transactions on Electron Devices, Vol. 47, No. 12, December 2000, pages 2320-2325.						
	Yang-Kyu Choi et al., "Sub-20nm CMOS FinFET Technologies," 2001 IEEE, IEDM, pages 421-424.						
	Xuejue Huang et al., "Sub-50 nm P-Channel FinFET," IEEE Transactions on Electron Devices, Vol. 48, No. 5, May 2001, pages 880-886.						
	Xuejue Huang et al., "Sub 50-nm FinFET: PMOS," 1999 IEEE, IEDM, pages 67-70.						
<i>J. An</i>	Yang-Kyu Choi et al., "Nanoscale CMOS Spacer FinFET for the Terabit Era," IEEE Electron Device Letters, Vol. 23, No. 1, January 2002, pages 25-27.						
<i>J. An</i>	Co-pending U.S. Application Serial Number 10/348,758 filed January 23, 2003 entitled, "GERMANIUM MOSFET DEVICES AND METHODS FOR MAKING SAME," Judy Xilin An et al., 22 page specification, 29 sheets of drawings.						
<b>EXAMINER</b> <i>J. An</i>	<b>DATE CONSIDERED</b> <i>2/28/04</i>						

EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant(s).

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